

Search Query Case No. 10/705,970

118	(356/503).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
103	(356/504).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
199	(356/630).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
280	(356/632).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
220	((356/503).CCLS.) or ((356/504).CCLS.)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
220	(356/503, 504).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
648	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
317	((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and transparent	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
221	((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (measuring with thickness with film)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
133	(((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (measuring with thickness with film)) and transparent	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
48	(((((356/503).CCLS.) or ((356/504).CCLS.)) and (measuring with thickness with film)) and transparent	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
48	((((((356/503).CCLS.) or ((356/504).CCLS.)) and (measuring with thickness with film)) and transparent) and reflect\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB

46	(((356/503).CCLS.) or ((356/504).CCLS.)) and (measuring with thickness with film)) and transparent) and reflected	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
77	(((356/503).CCLS.) or ((356/504).CCLS.)) and (measuring with thickness with film)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
649	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
275	(((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and phase	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
1	(((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (phase with spectr\$3 with (calculated or determined))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
25	(((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (phase with spectr\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
249	(((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and frequency	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
321	(((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and film and thickness and measuring	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
147	(((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and frequency) and (((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and film and thickness and measuring)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
102	(((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and film and thickness and measuring) and (frequency and based)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
12	(((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and film and thickness and measuring) and (frequency with based)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
2	(((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and film and thickness and measuring) and ((frequency or phase) with spectr\$4 with (waveform or distribution))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
649	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB

148	((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and measuring and film and thickness and pattern	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
2	((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and measuring and film and thickness and (step adj pattern)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
321	((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and measuring and film and thickness	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
306	(((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and measuring and film and thickness) and reflect\$5	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
81	(((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and measuring and film and thickness) and reflect\$5) and irradiat\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
175	(((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and measuring and film and thickness) and reflect\$5) and spectr\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
14	(((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and measuring and film and thickness) and reflect\$5) and (spectral with (waveform or distribution))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
97	((((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and measuring and film and thickness) and reflect\$5) and spectr\$3) and phase	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
111	(((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and measuring and film and thickness) and precision	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
53	(((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and measuring and film and thickness) and precision) and nm	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
5	(((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and measuring and film and thickness) and (precision with nm)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
0	jp-0752032-\$.did.	JPO; DERWENT
2	jp-07052032-\$.did.	JPO; DERWENT
221	((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (measuring with thickness with film)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB

32	((((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (measuring with thickness with film) and compare	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
1	("5,416,594").PN.	USPAT
1	("4,707,611").PN.	USPAT
131	(356/503).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
109	(356/504).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
251	(356/630).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
289	(356/632).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
718	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
1251	film with measur\$6 with phase\$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
364	film with measur\$6 with thickness with phase\$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
770	film with measur\$6 with precision\$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
275	film with measur\$6 with thickness with precision\$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
116	film\$1 with measuring with thickness with precision\$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
50	(film\$1 with measuring with thickness with precision\$1) and reflect\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB

46	(film\$1 with measuring with thickness with precision\$1) and (reflect\$2 with light\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
0	film\$1 with measuring with thickness with precision\$1 with (at adj least)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
718	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
0	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (fit\$ with (mathematical adj model\$1) with wavelength\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
5	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (fit\$ with (mathematical adj model\$1))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
13	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (fit\$4 with mathematical with model\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
48	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (film with measur\$5 with phase\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
38	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (film with measur\$5 with thickness with phase\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
38	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (film with measur\$5 with thickness with phase\$1)) and reflect\$5	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
269	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (interfer\$ and phase\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
100	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (interferometer and phase\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
22	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (interferometer with phase\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
136	(356/503).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB

119	(356/504).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
279	(356/630).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
297	(356/632).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
760	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
257	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.) and (measuring with thickness with film)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
55	((356/503).CCLS.) or ((356/504).CCLS.) and (measuring with thickness with film) and transparent	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
32	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.) and (phase with spectr\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
143	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.) and film and thickness and measuring) and (frequency and based)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
100	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.) and measuring and film and thickness) and reflect\$5) and irradiat\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
18	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.) and measuring and film and thickness) and reflect\$5) and (spectral with (waveform or distribution))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
131	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.) and measuring and film and thickness) and precision	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
67	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.) and measuring and film and thickness) and precision) and nm	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
56	(film\$1 with measuring with thickness with precision\$1) and (reflect\$2 with light\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB

13	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (fit\$4 with mathematical with model\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
53	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (film with measur\$5 with phase\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
23	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (interferometer with phase\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
20703	measur\$3 with film\$1 with thickness\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
3744	measur\$3 with film\$1 with thickness\$2 with method	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
40	measur\$3 with film\$1 with thickness\$2 with different with position\$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
834	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
376	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (film\$1 with thickness\$2 with measur\$5)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
353	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (film\$1 with thickness\$2 with measur\$5)) and method\$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
255	((356/503).CCLS.) or ((356/504).CCLS.) or ((356/630).CCLS.) or ((356/632).CCLS.)) and (film\$1 with thickness\$2 with measur\$5)) and (method\$1 with step\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
18	US-3612692-\$.DID. OR US-4293224-\$.DID. OR US-4606641-\$.DID. OR US-4660980-\$.DID. OR US-4666305-\$.DID. OR US-4748329-\$.DID. OR US-4984894-\$.DID. OR US-4999014-\$.DID. OR US-4999508-\$.DID. OR US-5440141-\$.DID. OR US-5452091-\$.DID. OR US-5555471-\$.DID. OR US-5587792-\$.DID. OR US-5610716-\$.DID. OR US-5856871-\$.DID. OR US-6137575-\$.DID. OR US-6142855-\$.DID. OR US-6348967-\$.DID.	USPAT

Search Results Case No. 09/622,570

US 6102775 A	USPAT	Film inspection method	451/6
US 5740226 A	USPAT	Film thickness measuring and film forming method	378/70
US 4434025 A	USPAT	Controlling crystallinity and thickness of monocrystalline layer by use of an elliptically polarized beam of light	117/86
US 6348967 B1	USPAT	Method and device for measuring the thickness of opaque and transparent films	356/432
US 5587792 A	USPAT	Apparatus and method for measuring thickness of thin semiconductor multi-layer film	356/497
US 5657123 A	USPAT	Film thickness measuring apparatus, film thickness measuring method and wafer polishing system measuring a film thickness in conjunction with a liquid tank	356/503
US 5513533 A	USPAT	Detection of vibrational energy via optical interference patterns	73/657
US 5440141 A	USPAT	Method of measuring a thickness of a multilayered sample using ultraviolet light and light with wavelengths longer than ultraviolet	250/559.27
US 4984894 A	USPAT	Method of and apparatus for measuring film thickness	356/632
US 4355903 A	USPAT	Thin film thickness monitor	356/632
US 4660980 A	USPAT	Apparatus for measuring thickness of object transparent to light utilizing interferometric method	356/504
US 4367044 A	USPAT	Situ rate and depth monitor for silicon etching	356/504
US 3612692 A	USPAT	DIELECTRIC FILM THICKNESS MONITORING AND CONTROL SYSTEM AND METHOD	356/492
US 6137575 A	USPAT	Film thickness measuring method and apparatus	356/503
US 5555471 A	USPAT	Method for measuring thin-film thickness and step height on the surface of thin-film/substrate test samples by phase-shifting interferometry	356/504
US 5610716 A	USPAT	Method and apparatus for measuring film thickness utilizing the slope of the phase of the Fourier transform of an autocorrelator signal	356/479
US 5523840 A	USPAT	Method and apparatus for measuring the thicknesses of layers of a multiple layer semiconductor film utilizing the comparison between a spatialgram and an optical characteristic matrix	356/497
US 5856871 A	USPAT	Film thickness mapping using interferometric spectral imaging	356/503

US 4293224 A	USPAT	Optical system and technique for unambiguous film thickness monitoring	356/504
US 4666305 A	USPAT	Film thickness measuring apparatus employing intensity compensation device of spectral reflectivity	356/632
US 5798837 A	USPAT	Thin film optical measurement system and method with calibrating ellipsometer	356/369
US 3861804 A	USPAT	INTERFEROMETRY READOUT OF PHASE INFORMATION	356/504
US 4606641 A	USPAT	Apparatus for measuring film thickness	356/369
US 6142855 A	USPAT	Polishing apparatus and polishing method	451/67
US 5754296 A	USPAT	Ellipsometric microscope	356/369
US 5452091 A	USPAT	Scatter correction in reflectivity measurements	356/445
US 4748329 A	USPAT	Method for on-line thickness monitoring of a transparent film	250/559.28
US 4999508 A	USPAT	Optical film thickness measuring device for measuring two-layer film thicknesses using spectral reflectance	250/559.27
US 4999509 A	USPAT	Optical measuring device of film thickness	250/559.27
US 6307627 B1	USPAT	Optical measurement system using polarized light	356/369